

## **EMIRS200** with Reflector 1

## Thermal MEMS Based Infrared Source



#### 1. Infrared Source

Axetris infrared (IR) sources are micro-machined, electrically modulated thermal infrared emitters featuring true blackbody radiation characteristics, low power consumption, high emissivity and a long lifetime. The patented design is based on a resistive heating element deposited onto a thin dielectric membrane which is suspended on a micro-machined silicon structure.

# 2. Infrared Gas Detection Applications

#### **Measurement Principles**

Non-dispersive infrared spectroscopy (NDIR), photo- acoustic infrared spectroscopy (PAS) or attenuated-total-reflectance FTIR spectroscopy (ATR)

#### **Target Gases**

CO, CO<sub>2</sub>, VOC, NO<sub>X</sub>, NH<sub>3</sub>, SO<sub>X</sub>, SF<sub>6</sub>, hydrocarbons, humidity, anesthetic agents, refrigerants, breath alcohols

#### Medical

Capnography, anesthesia gas monitoring, respiration monitoring, pulmonary diagnostics, blood gas analysis

#### **Industrial Applications**

Combustible and toxic gas detection, refrigerant monitoring, fruit ripening monitoring, SF<sub>6</sub> monitoring, semiconductor fabrication

#### **Environmental**

Heating, ventilating and air conditioning (HVAC), indoor air quality and VOC monitoring, air quality monitoring

#### **Automotive**

Automotive refrigerant monitoring, alcohol detection & interlock, cabin air quality

#### 3. Features

- Reflector 1 optimized for a source to detector distance<sup>1</sup> of up to 15 mm.<sup>2</sup>
- Large modulation depth at high frequencies
- Broadband emission: true black body radiation (2 to  $>17 \mu m$ )
- Very fast electrical modulation (no chopper wheel needed)
- Long lifetime
- Suitable for portable and very small applications
- Rugged MEMS design

 $<sup>^{\</sup>rm 1}{\rm Measured}$  from the top of the reflector.

<sup>&</sup>lt;sup>2</sup>Can be optimized with additional optical elements (or a reflective inner surface of the gas cell).



## 4. Electrical Parameters (T<sub>A</sub> = 22 °C)

Parameter	Symbol	Unit	Value Typical	Value Range
Electrical cold resistance <sup>3</sup>	R <sub>C22</sub>	Ω	45	35-55
Frequency	F	Hz	5	5-50
Duty cycle of rectangular V <sub>E</sub> pulse	D	%	50	30-70

## 5. Recommended Operating Conditions (ROC) at $T_A = 22 \, ^{\circ}$ C

Parameter	Symbol	Unit	Values or Equation
Frequency	f	Hz	5
Duty cycle of rectangular $V_E$ pulse	D	%	50
Electrical Power for R <sub>C22</sub> range	P <sub>E</sub>	mW	450
Voltage for $R_{C22} = 45 \Omega$	VE	V	5.6
Voltage computation	V <sub>E</sub> (R <sub>C22</sub> )	V	$0.052 \text{ V/}\Omega \times R_{C22} + 3.3 \text{ V}$

#### Operation mode power control

• Drive the EMIRS200 with the recommended electrical power  $P_E = 450$  mW at a frequency of 5 Hz and a duty cycle of 50 %.

#### Operation mode voltage control

- Determine the cold resistance R<sub>C22</sub>
- Compute the recommended operating voltage  $V_E$  (R<sub>C22</sub>) using the equation "Voltage computation".
- Apply a square wave signal (0 V to  $V_E$ ) at 5 Hz frequency and 50 % duty-cycle.

Non-modulated (DC) and operation mode current control are not recommended.

The Labkit and the Power Control PCB supplied by Axetris allow quick experimenting. A detailed technical note describing advanced operation modes is available upon request.

<sup>&</sup>lt;sup>3</sup> Value at delivery date

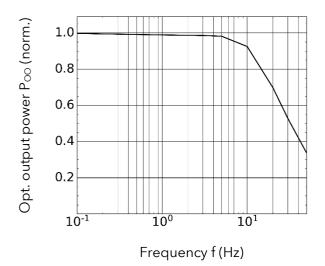


## 6. Ratings at Recommended Operating Conditions (ROC)

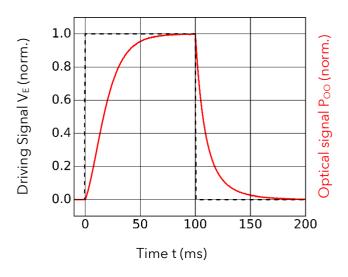
f = 5 Hz, duty-cycle 50 % at  $T_A = 22$  °C

Parameter	Symbol	Unit	Typical Rating
Optical output power <sup>45</sup> (hemispherical) for article without window	P <sub>oo</sub>	mW	28
Emissivity (2 μm-17 μm)	€	-	> 0.85
On time constant of optical output power $P_{00}$ (0% - 63%)	$ au_{on}$	ms	22 ± 1
Off time constant of optical output power $P_{00}$ (100% - 37%)	$ au_{ ext{off}}$	ms	11 ± 2
Electrical hot resistance computation	R <sub>H</sub> (R <sub>C22</sub> )	Ω	$1.5 \times R_{C22} + 2.8 \Omega$
Package temperature (TO Header) <sup>6</sup>	T <sub>P</sub>	°C	< 80

## 7. Typical Dynamic Characteristics



Normalized max-min values of optical output power  $P_{OO}$  versus frequency f with fixed  $V_{E}$ 



Normalized (to ROC) electrical driving signal  $V_E$  (t) (black, dashed), optical response  $P_{OO}$  (t) (red, solid)

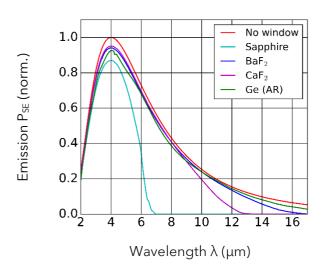
<sup>&</sup>lt;sup>4</sup>For pulsed operation: peak to peak signal

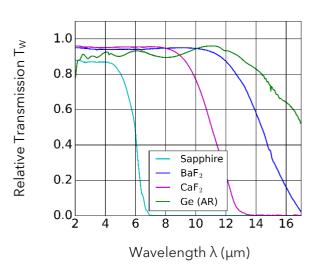
 $<sup>^5</sup>$ Refers to the measured value at ROC. The influence of the reflector geometry is based on simulation. Driving at higher  $V_H$  or  $P_H$  leads to an increase of  $P_{OO}$ , however with detrimental effects on lifetime.

<sup>&</sup>lt;sup>6</sup>TO Header vertically oriented, free convective cooling to air



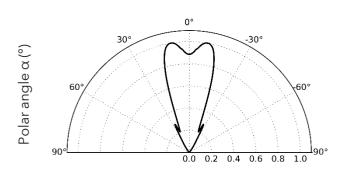
## 8. Typical Optical Characteristics (ROC)





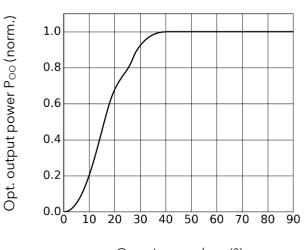
Emission spectrum  $P_{SE}\left(\lambda\right)$  without window and with windows of different materials

Window transmission spectra  $T_W\left(\lambda\right)$  of different materials



Radiant intensity  $I_{\Omega}(\alpha)$  (norm.)

Directivity plot showing radiant intensity  $^{7}$   $I_{\Omega}$  ( $\alpha$ ) emitted per polar angle  $\alpha$ 



Opening angle  $\alpha$  (°)

Normalized optical output power  $^7$   $P_{00}$  (integral from  $0^\circ$  to  $\alpha$ ) versus opening angle  $\alpha$ 

<sup>&</sup>lt;sup>7</sup>Simulated data

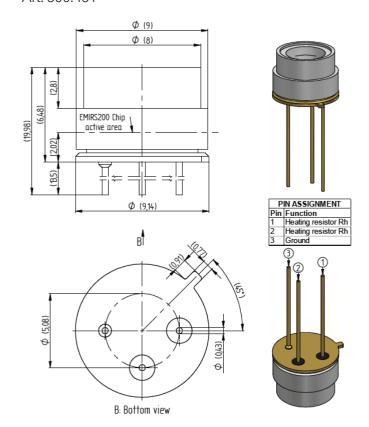


## 9. Article Overview and Dimensions

Article Type	Window Material	Art. No. Front-Vented <sup>8</sup>	Art. No. Back-Vented <sup>9</sup>
	No window	600.451	-
	BaF <sub>2</sub>	602.992	602.964
Reflector 1 on TO39 header	CaF <sub>2</sub>	602.993	602.965
	Sapphire	602.994	602.966
	Ge (AR)	602.989	602.961

Membrane area:  $2.0 \times 2.0 \text{ mm}^2$ 

#### Art. 600.451



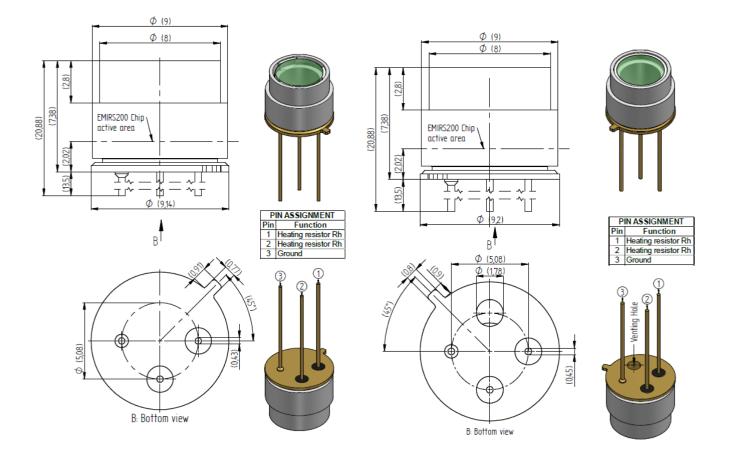
 $<sup>^{8}\</sup>mbox{Window}$  (if fitted) glued at 3 points to allow venting.

<sup>&</sup>lt;sup>9</sup>Window (if fitted) glued circumferentially. Gas tightness between window and the remainder of the IR source is not tested or guaranteed.



Art. 602.989, 602.992, 602.993, 602.994

Art. 602.961, 602.964, 602.965, 602.966





### 10. Environmental Information

Parameter	Symbol	Rating	Unit
Storage temperature	Ts	-40 to +125	°C
Operating temperature	To	-40 to +85	°C
Relative humidity	RH	0 to 85 non-condensing	%

## 11. Reliability Information

- Lifetime: >100000 h MTTF<sup>10</sup> at ROC
- ESD: Devices are not sensitive to electro-static discharge.
- Mechanical shock and vibration tests were performed according to IEC 60601-1:2005 and ISO 80601-2-55:2018 in accordance with the following methods:
- Mechanical shock: IEC 60068-2-27:2009, according to IEC 60721-4-7:1995, Class 7M3
- Vibration broadband random: IEC 60068-2-27:2009, according to IEC 60721-4-7:1995, Class 7M3.

All tested devices passed.

- Environmental stress tests:
- Temperature cycling shock (non-operating) tests were performed according to JESD22-A104C:2005, Test condition G: -40 °C to +125 °C.
- Temperature humidity tests during operation were performed according to IEC 60068-2-67:2019, Test Cy: Severity I, Damp heat, 85 °C, 85 % RH.

All tested devices passed.

 Additional testing was performed, detailed information is available upon request.

- Drift of electrical resistance and optical output power:
- Operating the EMIRS200 in either modulated or continuous mode results in an irreversible steady increase in the electrical resistance over time that eventually saturates. The electrical resistance drift is accompanied by a change in optical output power.
- We recommend regular or continuous recalibration of the detector signal to mitigate the influence of resistance and output power drift.
- The electrical resistance drift is minimized by modulating the source during operation.
   When operating in DC, enhanced levels of drift in electrical resistance and optical output are observed.

More information and guidance available upon request.

 The EMIRS200 should not be sealed hermetically. For solutions or questions regarding hermetical sealing please contact our application engineering.

<sup>&</sup>lt;sup>10</sup> MTTF: mean time to failure, i.e. the time until 63 % of the devices have failed.



## 12. Handling Precautions

- Do not touch the chip surface.
- Do not clean the sources.
- Process under cleanroom conditions.
  Use suitable gloves (nitril or powder-free Latex) for handling.

## 13. Conformity assessment

The IR sources are developed and produced in compliance with the standard EN ISO9001:2015 (see website).

#### **RoHS and REACH compliance**

The IR source falls under the directive of the restriction of the use of certain hazardous substances in electrical and electronic equipment 2011/65/EC. A copy of the latest RoHS and REACH Compliance documents as well as the documents for Conflict Minerals Reporting (CMRT) and Extended Minerals Reporting (EMRT) are available on request.

#### 14. Disclaimer

The information provided by Axetris is believed to be correct and accurate. However, Axetris shall not be liable to the recipient or any third party for any damages, including but not limited to, personal injury, property damage, loss of profits, loss of use, interrupt of business or indirect, special incidental or consequential damages, of any kind, in connection with or arising out of the furnishing, performance or use of technical data herein. No obligation or liability to recipient or any third party shall arise from the provision of technical or other services by Axetris.

Specifications are subject to change without prior notice.